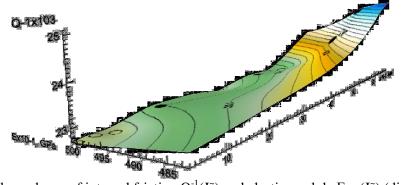
## Inelastic Defect Characteristic Internal Friction in SiO<sub>2</sub>, GeSi and Anisotropy Automated System "KERN-DP"

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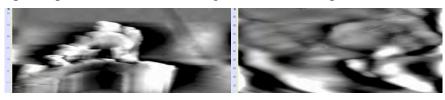
Influence of direct and variable electrical current is considered at simultaneous act of ultrasonic deformation on internal friction (IF) and elastic module of GeSi single-crystal after cutting and polishing. The diminishing of elastic module E of and the growth of internal friction  $Q^{-1}$  is found out at achievement of critical value of electrical current. Kinetics of annealing of structural defects is studied.

The results of examinations of the relaxation processes in a crystalline lattice at thermal and ultrasonic (US) processing on the temperature spectrum of internal friction and elastic module (directional surface of inelastic-elastic body) of SiO<sub>2</sub>, GeSi are presented. The growth of IF Q<sup>-1</sup>( $J^{\sim}$ ) is observed for an alternating current  $J^{\sim}$  at achievement of critical value of electrical current thickness  $J_{cr}^* \approx 60^{\circ}10^3$  A/m<sup>2</sup> with the simultaneous diminishing of the elastic module value E( $J^{\sim}$ ) at the consequent increasing of current thickness, as evidently from fig. 1.



**Fig. 1.** Current dependence of internal friction  $Q^{-1}(J^{\sim})$  and elastic module  $E_{111}(J^{\sim})$  (directional surface inelastic-elastic body) of monocrystal GeSi after cutting and polishing from an alternating electrical current thickness with frequency  $\omega_J = \omega_{US}$ .

The software "KERN-DP" is developed for the automated system of anisotropy parameters analysis. The structure of database is developed on language of mySQL information, physical properties, the special procedures of data management are developed.



**Fig. 2.** Atomic force microscopy microstructure of  $SiO_2$  pores on Si (100) ( $15x15x10^3$  nm;  $1x1x10^3$  nm).

## Conclusions

1. The measuring of internal friction background  $Q^{-1}_0$  after different heat, mechanical, radiation treatments gives information about the changing of the thermoelastic strains fields  $\sigma_i$  in SiO<sub>2</sub>.

2. The dynamic characteristics of interstitial atoms  $Si_j$ , vacancy V and O-complexes can be applied for account of a condition of an annealing with the purpose of deriving specific structural defects in SiO<sub>2</sub>.